



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/655,997
Filing Date September 5, 2003
Confirmation No. 7524
Inventor Jon P. Daley
Assignee Micron Technology, Inc.
Group Art Unit 2822
Examiner Pamela E. Perkins
Attorney's Docket No. MI22-2380
Customer No. 021567
Title: Methods of Forming Patterned Photoresist Layers Over Semiconductor
Substrates

RESPONSE TO AUGUST 8, 2005 FINAL OFFICE ACTION
PRELIMINARY AMENDMENT TO ACCOMPANY RCE FILING

To: Mail Stop RCE
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

VIA U.S. EXPRESS MAIL

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)
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Responsive to the Final Office Action dated August 8, 2005, Applicant
amends and remarks as follows:

AMENDMENTS

12/05/2005 DEMMANU1 00000109 10655997

01 FC:1201 400.00 OP
02 FC:1202 200.00 OP

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